Abstract

Method for fabricating a trench isolation structure

5 A method for fabricating a trench isolation structure, including forming a mask on a substrate, forming at least one trench in the substrate with the mask, carrying out selective deposition of a first insulation material to at least partially fill the at least one trench in the substrate with the insulation material in the presence of the mask, and applying a second insulation material over the entire surface of the structure in order to fill the at least one trench in the substrate at least up to the top side of the mask.